

**HIGH RESOLUTION FIELD EMISSION SCANNING ELECTRON MICROSCOPE:
HITACHI S-4800 SETUP FOR EDX**

1. Put specimen into chamber
2. Switch on monitor for EDX
3. Open program "Esprit" on desktop
4. Lower Sa 10005000 in F.0 1 (p00000.2600.2%.80004 655.44 cm 10005000 in 219.7805T(c